

EAST Search History

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
S1	4	"6891218"	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2006/10/25 17:36
S2	2091	mim capacitor	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2006/06/11 18:03
S3	95	mim capacitor and etch\$3 with ("cl. sub.2" or "chf.sub.3" or Ar)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2006/06/11 18:05
S4	48	mim capacitor and etch\$3 with ("cl. sub.2" or "chf.sub.3" or Ar) and ti	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2006/10/25 23:11
S5	56	mim capacitor and etch\$3 with ("cl. sub.2" or "chf.sub.3" or Ar) and tin	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2006/06/11 18:05
S6	0	mim capacitor and etch\$3 with ("cl. sub.2" or "chf.sub.3" or Ar) and tin plasma	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2006/06/11 18:06
S7	52	mim capacitor and etch\$3 with ("cl. sub.2" or "chf.sub.3" or Ar) and tin and plasma	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2006/06/11 18:06
S8	36	mim capacitor and etch\$3 with ("cl. sub.2" or "chf.sub.3" or Ar) and tin and plasma with etch\$3	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2006/06/11 18:30

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S9	14	mim capacitor and etch\$3 with ("cl. sub.2" or "chf.sub.3" or Ar) and tin and plasma with etch\$3 and rie	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2006/10/25 23:12
S10	2	("6100201").PN.	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/07/07 23:25
S11	2608	(438/253).CCLS.	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/10/25 23:11
S12	4584	(438/396).CCLS.	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/10/25 23:11
S13	631	(438/712).CCLS.	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/10/25 23:11
S14	2	("6100201").PN.	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/10/25 18:36
S15	2192	insulator and metal and capacitor and etch\$3 with condition	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2006/10/25 18:37
S16	543	insulator same etch\$3 with condition	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2006/10/25 18:37

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S17	22	insulator same different with etch\$3 with condition	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2006/10/25 18:38
S18	4	metal same insulator same different with etch\$3 with condition	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2006/10/25 18:38
S19	2675	(438/253).CCLS.	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/10/25 23:11
S20	4652	(438/396).CCLS.	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/10/25 23:11
S21	643	(438/712).CCLS.	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/10/25 23:11
S22	58	mim capacitor and etch\$3 with ("cl. sub.2" or "chf.sub.3" or Ar) and ti	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2006/10/25 23:11
S23	13	mim capacitor and etch\$3 with ("cl. sub.2" or "chf.sub.3" or Ar) and tin and plasma with etch\$3 and rie	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2006/10/25 23:19
S24	13	mim capacitor and etch\$3 with ("cl. sub.2" or "chf.sub.3" or Ar) and tin and plasma with etch\$3 and rie	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2006/10/25 23:19